well as Semiconductor Device Inventors: SHINTANI ET AL. Atty Docket No.: 401352

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FIG.1

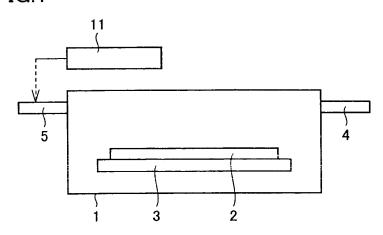
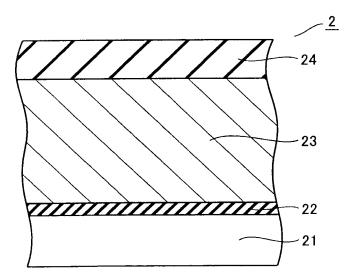


FIG.2



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FIG.3

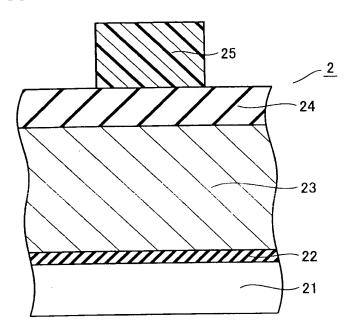
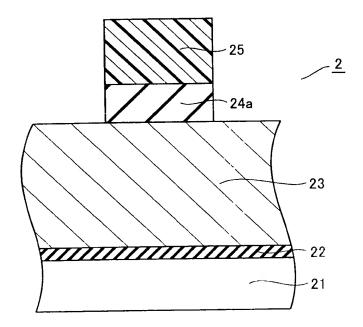


FIG.4



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FIG.5

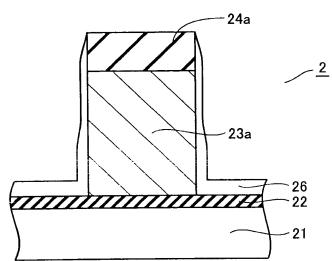
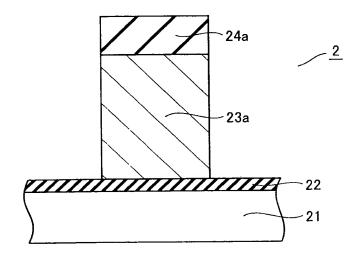


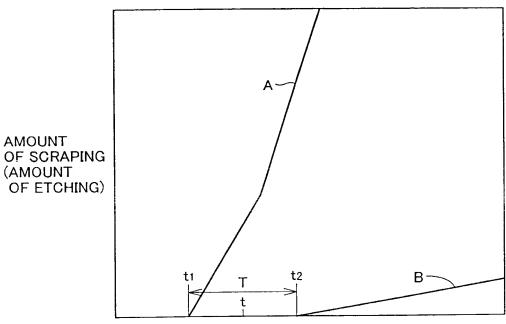
FIG.6



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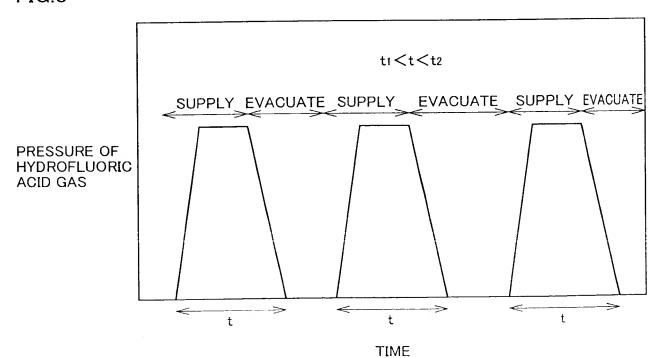
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FIG.7



TIME AFTER STARTING SUPPLYING HYDROFLUORIC ACID GAS INTO CHAMBER

FIG.8



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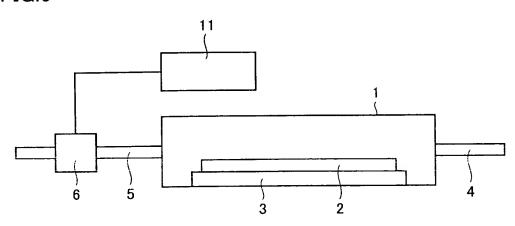
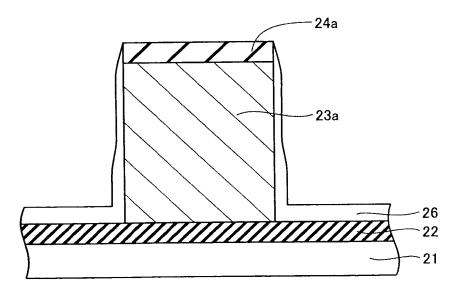


FIG.10



Title: Method of Fabricating Semiconductor Device and Wafer Treatment Apparatus Employed Therefor as well as Semiconductor Device

well as Semiconductor Device Inventors: SHINTANI ET AL. Atty Docket No.: 401352

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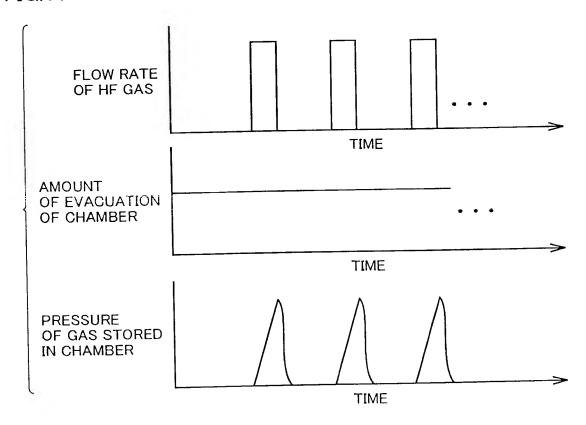
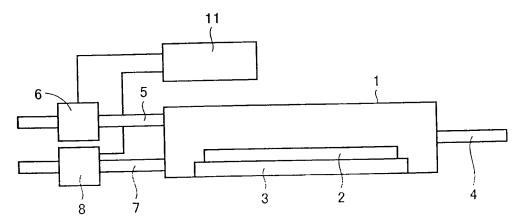
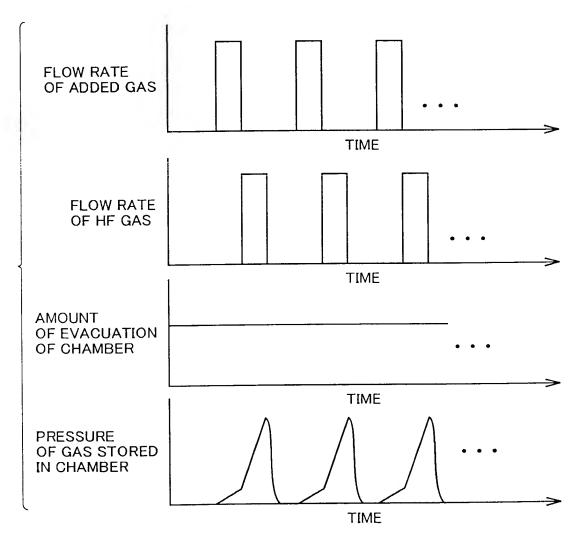


FIG.12



well as Semiconductor Device Inventors: SHINTANI ET AL. Atty Docket No.: 401352 Leydig, Voit & Mayer, Ltd. 202

FIG.13



well as Semiconductor Device Inventors: SHINTANI ET AL. Atty Docket No.: 401352 Leydig, Voit & Mayer, Ltd. 202

FIG.14

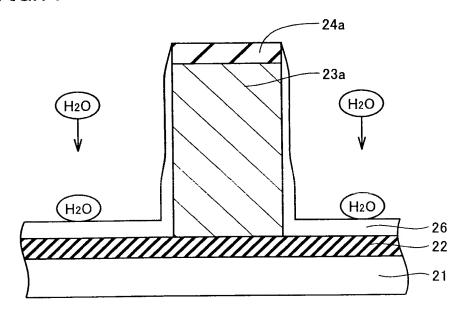
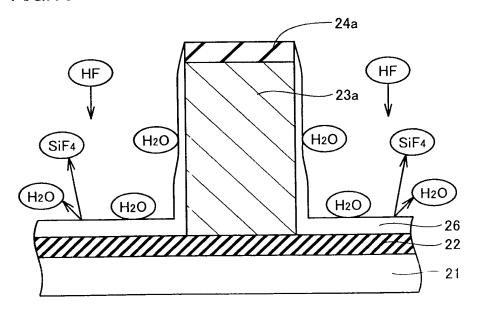


FIG.15



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FIG.16

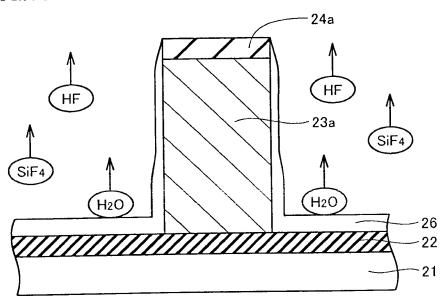
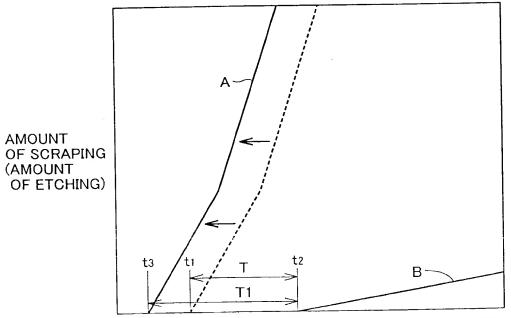


FIG.17



TIME AFTER STARTING SUPPLYING HYDROFLUORIC ACID GAS INTO CHAMBER

well as Semiconductor Device Inventors: SHINTANI ET AL. Atty Docket No.: 401352

Leydig, Voit & Mayer, Ltd. 202-737-6770

FIG.18

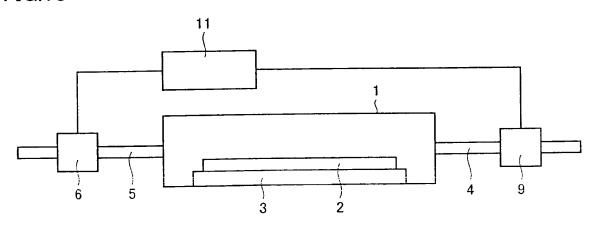
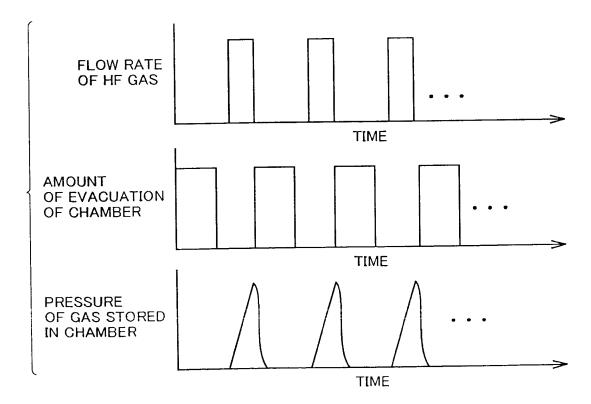


FIG.19



well as Semiconductor Device Inventors: SHINTANI ET AL. Atty Docket No.: 401352

Leydig, Voit & Mayer, Ltd.

FIG.20

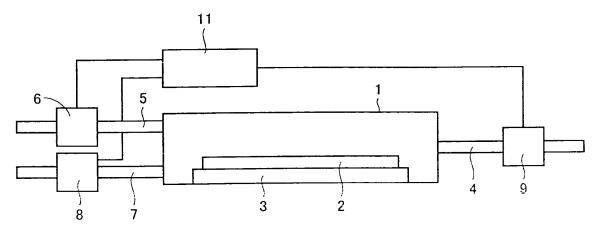
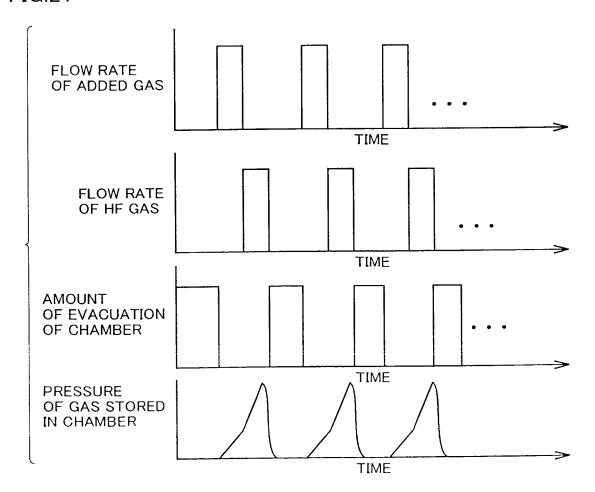


FIG.21



well as Semiconductor Device Inventors: SHINTANI ET AL.

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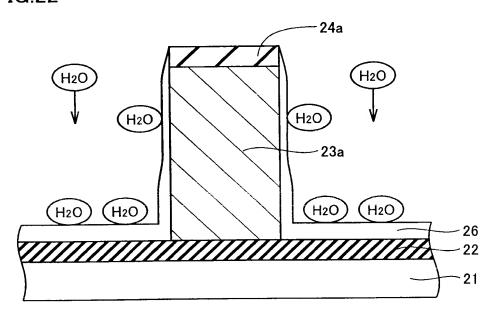
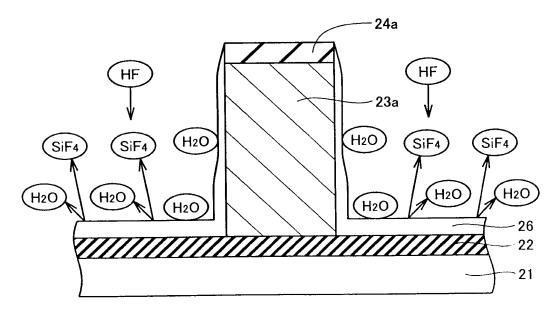


FIG.23



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FIG.24

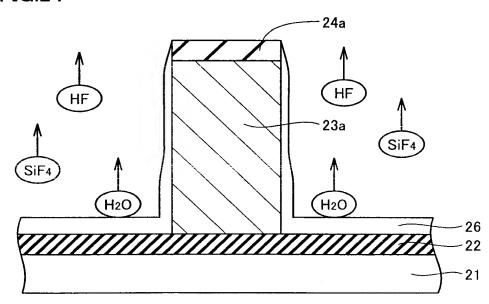
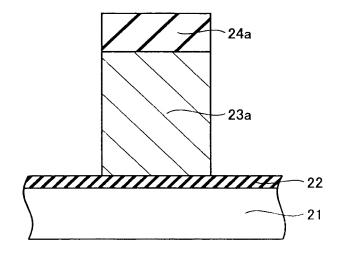


FIG.25



well as Semiconductor Device Inventors: SHINTANI ET AL. Atty Docket No.: 401352

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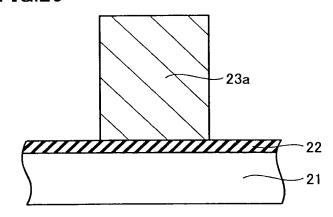


FIG.27 PRIOR ART

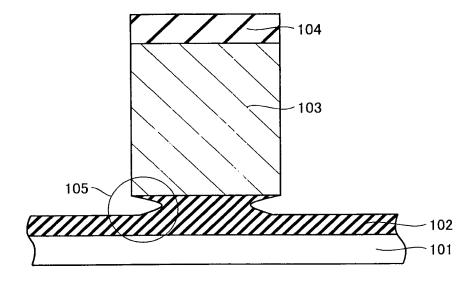
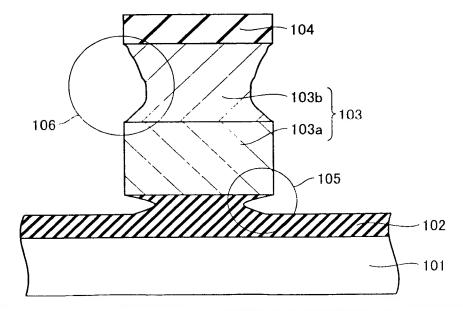


FIG.28 PRIOR ART



Title: Method of Fabricating Semiconductor Device and Wafer Treatment Apparatus Employed Therefor as well as Semiconductor Device Inventors: SHINTANI ET AL.

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FIG.29 PRIOR ART

